

Doubt Number (Specimen)

TSMC-01-1493

Afternoon Session

10/718,363

Applicant

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Filing Date

11/20/03

Group Art Unit

U. S. PATENT DOCUMENTS

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[illegible]

EXAMINER

DATE CONSIDERED

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EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP § 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to the applicant.